



IEC RESEARCH STATUS AT MSFC

Ivana Hrbud, Chris Dobson MSFC// TD40



EXPERIMENT SET-UP

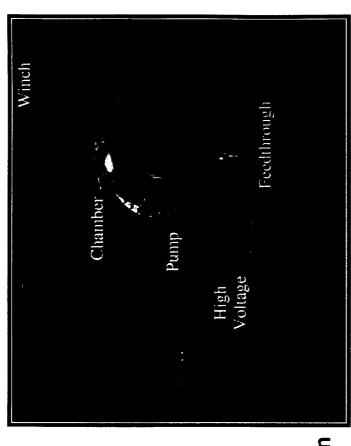


* Hardware Characteristics

- 2-foot Spherical Vacuum Chamber
- *5-kW High Voltage Power Supply by Hipotronics
- **⊕ 100 KV**
- 50 mA

❖ Diagnostics

- Neutron Detector (Ag Counter)
- Proton Detector (PD PIPS)
- Photon Emission Spectroscopy
- Laser Techniques under consideration
- Propellant Feed System based on Thermal Conductivity Mass Flow Control
- Hydrogen, Deuterium
- Mass Flow Control Calibration



* Planned Pulsed Mode Operation

- ❖ Pulse Width = 0.1 msec
- ❖ Peak Voltage = 100 kV
- ❖ Peak Current = 50 A
- ❖ Pulse Energy = 200 J



GRID MANUFACTURING



* Issues

Reproducibility (test data on designs)

* Sphericity

* Uniformity

Radial Potentials

* Identified Manufacturing Techniques

❖ Metal Deposition Techniques

Electro-Chemical Ni Plating: Easy Production of Templates with Stereolithography Wire Arc- and HVOF Flame- Sprays: SS Plating on Al Template, Al Plating on Stereolithographical Epoxy Template

Hollow Grid Fabrication (Cooling Channels) for High Power Applications

❖ Negative Template Mold

Stereolithography used in Fast-Prototyping Technology

• Metal O-rings provide Pre-fabricated Loops

Spot Welding of SS

❖ Machining

Electrostatic-Discharge Machining (EDM) & Stamping (or 3-D)

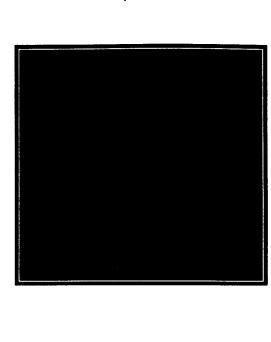
Laser Cutting (tentative)



GRID FOR IEC OPERATION



- * Negative Template Technique
- * Template is made with Stereolithography Technique
- Template provides
- grooves for arranging SS loops into proper position and
- holes for spot welding the loops together.



* Electro-Chemical Technique

- * Template is made with Stereolithography Technique.
- Template is coated with conductive paint.
- Template is submerged in a Nickel-Sulfamate bath.
- ❖ Nickel coating is ≅ 0.13 mm thick at 7 hours (in example shown)